

Customer No.: 31561
Application No: 10/719,593
Docket No.: 15866-US-PA

AMENDMENT

In the Specification:

Please amend paragraph 2 on page 7 as follows:

In Figure 2, it is shown a capacitor plate 10 which is positioned above a wafer surface 11 on which a two-dimensional distribution of electrostatic charges is to be measured. The wafer surface 11 may also include a dielectric layer 16 thereon. The capacitor plate 10 is controlled by a mechanical vibrator 12, which causes the wafer 11 to move vertically as well as horizontally. A movable probe 13, which is connected to a Kelvin probe electronics 14, is utilized to measure (i.e. scanning) voltages at various locations at the capacitor plate 10.